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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/519,084	12/23/2004	Heiji Watanabe	Q85504	7332
23373 SUGHRUE MI	7590 11/18/200 ON, PLLC	EXAMINER		
2100 PENNSY	LVANIA AVENUE, N	CHIU, TSZ K		
SUITE 800 WASHINGTOI	N, DC 20037		ART UNIT	PAPER NUMBER
			2822	
			NOTIFICATION DATE	DELIVERY MODE
			11/18/2009	ELECTRONIC

# Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Notice of the Office communication was sent electronically on above-indicated "Notification Date" to the following e-mail address(es):

sughrue@sughrue.com PPROCESSING@SUGHRUE.COM USPTO@SUGHRUE.COM

Office Action Summary		Applica	olication No. Applicant(s)					
		10/519	,084	WATANABE ET	WATANABE ET AL.			
		Examin	ier	Art Unit				
		Tsz K. (	Chiu	2822				
Period fo	The MAILING DATE of this communicat or Reply	tion appears on t	the cover sheet wit	h the correspondence a	ddress			
WHIC - Exter after - If NC - Failu Any r	ORTENED STATUTORY PERIOD FOR CHEVER IS LONGER, FROM THE MAIL asions of time may be available under the provisions of 3' SIX (6) MONTHS from the mailing date of this communical period for reply is specified above, the maximum statutor to reply within the set or extended period for reply will, reply received by the Office later than three months after the patent term adjustment. See 37 CFR 1.704(b).	ING DATE OF 7 CFR 1.136(a). In no cation.  by period will apply and by statute, cause the a	THIS COMMUNIC event, however, may a re d will expire SIX (6) MONT application to become ABA	CATION.  ply be timely filed  THS from the mailing date of this of the control of				
Status								
1)	Responsive to communication(s) filed of	on 06 July 2009						
,	•		non-final					
′=	This action is <b>FINAL</b> . 2b) This action is non-final.  Since this application is in condition for allowance except for formal matters, prosecution as to the merits is							
ت (د	closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.							
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· · ·	on of Claims	_						
•	Claim(s) <u>21-40</u> is/are pending in the ap							
	4a) Of the above claim(s) is/are withdrawn from consideration.							
	5)⊠ Claim(s) <u>21-36 and 40</u> is/are allowed.							
·	Claim(s) <u>37-39</u> is/are rejected.							
•	Claim(s) is/are objected to.							
8)[	Claim(s) are subject to restriction	n and/or electior	requirement.					
Applicati	on Papers							
9)	The specification is objected to by the E	xaminer.						
10)	The drawing(s) filed on is/are: a)	☐ accepted or	b) objected to b	y the Examiner.				
	Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).							
	Replacement drawing sheet(s) including the	correction is req	uired if the drawing(s	s) is objected to. See 37 C	FR 1.121(d).			
11)	The oath or declaration is objected to by	the Examiner.	Note the attached	Office Action or form P	TO-152.			
Priority ι	ınder 35 U.S.C. § 119							
	Acknowledgment is made of a claim for ☑ All b) ☐ Some * c) ☐ None of:		_	119(a)-(d) or (f).				
	1. Certified copies of the priority documents have been received.							
	2. Certified copies of the priority documents have been received in Application No							
	3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).							
* C		•		raccivad				
	See the attached detailed Office action fo	or a list of the ce	itilied copies not i	eceived.				
Attachmen	t(s)							
	e of References Cited (PTO-892)			ummary (PTO-413)				
	e of Draftsperson's Patent Drawing Review (PTO- nation Disclosure Statement(s) (PTO/SB/08)	948)		)/Mail Date formal Patent Application				
Paper No(s)/Mail Date 6) Other:								

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### **DETAILED ACTION**

## Response to Arguments

Applicant's arguments filed 7/6/09 have been fully considered but they are not persuasive. Applicant argue that Lee et al. (6844604) fail to disclose a gate insulating film, gate electrode, wherein the gate insulating film comprising two layer, first insulating film layer comprise silicon oxide and second silicon oxide film comprise of silicon oxynitride however, Lee disclose these limitation, gate insulating film (15, for example figure. 2) and gate electrode (24, for example figure. 2) stacked in this order on the substrate, wherein the gate insulating film comprising a first silicon oxide film, (12, For example Fig. 2) and a second silicon oxynitride film (14, For example Fig. 2). Therefore the rejection on claims 37-39 are proper.

## Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 37-39 are rejected under 35 U.S.C. 102(e) as being anticipated by Lee et al. (6844604).

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With respect to claim 37, Lee discloses a semiconductor device stacked a gate insulating film (15, for example figure. 2) and a gate electrode (24, for example figure. 2) stacked in this order on a silicon substrate (10, for example figure. 2); wherein

said gate insulating film (15, for example figure. 2) has a layered structure having, from the silicon substrate side (10, for example figure. 2), a first silicon oxide film ((reference numbered 12; column 4, lines 9-17) column 8, lines 30-35), a metal oxide film or a metal silicate film and a second silicon oxide film ((reference numbered 14; column 4, lines 3-5) column 8, lines 30-35); and

only the second silicon oxide film ((reference numbered 14; column 4, lines 3-5) column 8, lines 30-35) has a structure in which nitrogen is introduced into silicon oxide (column 4, lines 1-5).

With respect to claim 38, Lee discloses a semiconductor device according to Claim 21, wherein said silicon substrate (10, for example figure. 2) and said gate insulating film (15, for example figure. 2) are in contact with each other, and said gate insulating film (15, for example figure. 2) and a gate electrode (24, for example figure. 2) are in contact with each other; and said gate electrode is made of either a polysilicon or a polysilicon germanium conductive film (24, For example Fig. 2).

With respect to claim 39, Lee discloses the gate insulating film contains at least one type selected from the group consisting of Zr, Hf, Ta, A1, Ti, Nb, Sc, Y, La, Ce, Pr, Nd, Sm, Eu, Gd, Tb. Dy, Ho, Er, Tm, Yb and Lu (column 8, lines 50-55).

### Allowable Subject Matter

Claims 21-36,40 are allowed.

The following is a statement of reasons for the indication of allowable subject matter:

Claim 21 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film a position at which the nitrogen concentration in said nitrogen containing high-dielectric-constant insulating film reaches a maximum in the direction of the film thickness is present in a region at a distance from the silicon substrate.

Claim 29 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film a position at which the nitrogen concentration in said nitrogen containing high-dielectric-constant insulating film selectively bonds with a silicon atom in metal silicate.

Claim 34 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film nitrogen is introduced only into a region lying between the position at which the silicon concentration has the minimum value and said gate electrode side interface.

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Claim 40 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film a position at which the nitrogen concentration in said gate insulating film reaches a maximum in the direction of the film thickness is present in a region at a distance from the silicon substrate.

#### Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Tsz K. Chiu whose telephone number is 571-272-8656. The examiner can normally be reached on 0800 to 1700.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra V. Smith can be reached on 571-272-2429. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Zandra V. Smith/ Supervisory Patent Examiner, Art Unit 2822

/Tsz K Chiu/ Examiner, Art Unit 2822 November 8, 2009